Supporting Information

Nanostructured Surfaces of Opposite Charge from Self-Assembled Block Copolymers

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2. Glass apparatus used for HCl vapor treatments

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homopolymer, and C) RAFT CTA (CDPA).



Figure S2. ¹³C NMR (CDCl₃, 25 °C, 125 MHz) of CDPA, RAFT CTA.



Figure S3. ATR-IR spectrum of CDPA, RAFT CTA, at 25 °C.



Figure S4. ¹³C NMR (CDCl₃, 25 °C, 125 MHz) of PtBMA macro-CTA.



Figure S5. ATR-IR spectrum of PtBMA macro-CTA at 25 °C.



Figure S6. SEC-RI trace (THF mobile phase, 25 °C) of PtBMA macro-CTA ($M_n = 51.0$ kg mol⁻¹, D = 1.04) determined by MALS using a dn/dc = 0.065 mL/g.



Figure S7. ¹H NMR (CDCl₃, 25 °C) showing the integration ratios for P4VP-*b*-PtBMA used for determining molar ratios of each diblock copolymer segment.



Figure S8. ¹³C NMR (CDCl₃, 25 °C, 125 MHz) of PtBMA-*b*-P4VP.



Figure S9. ATR-IR spectrum of PtBMA-*b*-P4VP at 25 °C.



Figure S10. SEC-RI overlay trace (THF mobile phase, 25 °C) of PtBMA (black) and PtBMA-*b*-P4VP (red).



Figure S11. DSC thermogram of PtBMA-*b*-P4VP (exo up). Samples were cycled from 40 °C to 165 °C at a rate of 10 °C min⁻¹ under N₂ and the data shown was taken upon the 2^{nd} heating.



Figure S12. DSC thermogram of PtBMA macro-CTA (exo up). Samples were cycled from 40 °C to 165 °C at a rate of 10 °C min⁻¹ under N₂ and the data shown was taken upon the 2^{nd} heating.



Figure S13. TGA thermogram of PtBMA-*b*-P4VP taken at a heating rate of 10 °C min⁻¹ under Ar. A two-step thermal decomposition is observed.



Figure S14. Normalized intensity of negative ion detection as a function of ion dose determined by ToF-SIMS in negative ion mode for P4VP homopolymer.



Figure S15. Normalized intensity of negative ion detection as a function of ion dose determined by ToF-SIMS in negative ion mode for PtBMA homopolymer



Figure S16. Normalized intensity of positive ion detection as a function of ion dose determined by ToF-SIMS in positive ion mode for P4VP homopolymer.



Figure S17. Normalized intensity of positive ion detection as a function of ion dose determined by ToF-SIMS in positive ion mode of PtBMA homopolymer.



Figure S18. ToF-SIMS imaging of dewetted film**VP-MA(12-4)**. The characteristic ion images, here, $C_7H_8N^+$ (red) for P4VP and $C_8H_{13}O_2^+$ (blue) for PtBMA described a relatively homogeneous composition in the region without dewetting when the Si⁺ ion image displays the substrate in the bottom of the pits.

<u>Description and images of custom-built glassware apparatus for treatment of thin films with HCl vapor.</u>

A glass vial insert serves as the HCl reservoir which is housed within a pressure vessel that can be sealed with a PTFE cap and Viton o-ring (left picture). Another glass insert rests at the top of the pressure vessel and serves as a stage for the substrates to rest on (right picture). This glass insert has a bore in the center to allow HCl vapor exposure from the reservoir below.

